

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 02-230690

(43)Date of publication of application : 13.09.1990

(51)Int.Cl.

H05B 33/10

(21)Application number : 01-052552

(71)Applicant : FUJITSU LTD

(22)Date of filing : 03.03.1989

(72)Inventor : OKAMOTO KENJI

SATO KIYOTAKE

WATANABE KAZUHIRO

WATABE JUNICHI

HASEGAWA TADASHI

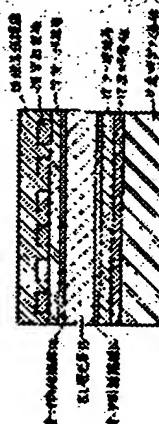
NAKAMURA KIMIYAKI

(54) THIN FILM EL PANEL

(57)Abstract:

PURPOSE: To enhance the luminance intensity and reliability by forming an EL light emitting layer as a thin film made by multi-element vapor deposition method using a vapor source consisting of light emitting layer constituting elements; and forming insulation layers provided on both sides of the light emitting layer as a thin film made by atomic layer epitaxial method.

CONSTITUTION: A transparent first insulation layer 13 which is 200 μ m thick and made of Al_2O_3 and others formed by atomic layer epitaxy using raw materials such as $AlCl_3$ is formed on the surface of a transparent electrode 12. An EL light emitting layer 15, 6000 μ m thick, is provided being formed by multi-element vapor deposition method using for example multiple vapor source of Zn and S constituting light emitting mother material, and Mn to be a light emitting central layer, via a first intermediate insulation film 14 comprising Al_2O_3 , Ta_2O_5 , and others formed by sputtering or vapor deposition method. Back plates 18 at right angles to the transparent electrode 12 are disposed to form a matrix on the light emitting layer 15 via a second insulation layer which is 2000 μ m thick and comprising a second intermediate insulation film 16 and Al_2O_3 , etc., formed by atomic layer epitaxial method.



BEST AVAILABLE COPY

LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]